PATENT APPLICATION

Docket Number: 081468-0302644 Client Reference: P-1698.000-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of FLAGELLO ET AL.

Application No.: 10/698,012

Filed: October 31, 2003

Group Art Unit: 2854

Examiner: Unassigned

Confirmation No.: 7154

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO-1449 to Applicants with the next Office Communication to indicate that the references have been considered, per MPEP § 609.

The undersigned notes that copies of U.S. references are not required in Information Disclosure Statements (IDS's) in applications filed after June 30, 2003. WO99/49504, submitted with the application on October 31, 2003, is being resubmitted with a translation.

This IDS is being filed (a) within three months of the U.S. filing date of this non-CPA application, or (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

PILLSBURY WANTHROP LLP

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